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PCT**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE****In re Application of:** Neumeier et al.**Docket No:** SCHO0059**Serial No. :** 09/868,156**Art Unit:** 2831**Filed:** September 14, 2001**Examiner:** Not Assigned**Title:** METHOD OF PRODUCING A MICRO-ELECTROMECHANICAL ELEMENT

February 23, 2005

Assistant Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450**INFORMATION DISCLOSURE STATEMENT**

Sir:

This Information Disclosure Statement is submitted:

- ☐ under 37 CFR 1.97(b), or
(within three months of filing national application; or date of entry of international application; or before mailing date of first office action on the merits; whichever occurs last)
- ☒ under 37 CFR 1.97(c) together with either a:
 - ☒ Certification under 37 CFR 1.97(e), or
 - ☐ a \$220.00 fee under 37 CFR 1.17(p), or
(After the CFR 1.97(b) time period, but before final action or notice of allowance, whichever occurs first)
- ☐ under 37 CFR 1.97(d) together with a:
 - ☐ Certification under 37 CFR 1.97(e), and
 - ☐ a \$220.00 fee under 37 CFR 1.17(d)(2)(ii), and
 - ☐ a \$130.00 petition fee set forth in 37 CFR 1.17(i)(1)
(Filed after final action or notice of allowance, whichever occurs first, but before payment of the issue fee)

(X) Applicant(s) submit herewith Form PTO 1449 -- Information Disclosure Citation together with copies of patents, publications or other information of which applicant(s) are aware, which applicant(s) believe(s) may be material to the examination of this application and for which there may be a duty to disclose in accordance with 37 CFR 1.25.

() A concise explanation of the relevance of foreign language patents, foreign language publications and other foreign language information listed on PTO Form 1449, as presently understood by the individual(s) designated in 37 CFR 156(c) most knowledgeable about the content is given on the attached sheet, or where a foreign language patent is cited in a search report or other action by a foreign patent office in a counterpart foreign application, an English language version of the search report or action which indicates the degree of relevance found by the foreign office is listed on form PTO 1449 and is enclosed herewith.

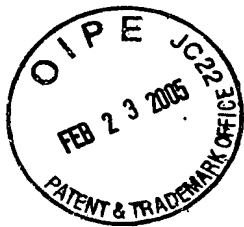
It is requested that the information disclosed herein be made of record in this application.

Respectfully Submitted,



Julia A. Thomas
Attorney For Applicant
Reg. No. 52,283

Customer No. 22862



PATENT

In re Application of: Neumeier et al.

Docket No: SCHO0059

Serial No. : 09/868,156

Art Unit: 2831

Filed: September 14, 2001

Examiner: Not Assigned

Title: METHOD OF PRODUCING A MICRO-ELECTROMECHANICAL ELEMENT

CERTIFICATION FOR INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR §§1.97(e)

Assistant Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

A certification is being made for the Information Disclosure Statement accompanying this certification.

CERTIFICATION

I, the person signing below, certify

(X) that each item of information contained in the information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the statement.
(37 CFR 1.97(e)(1))

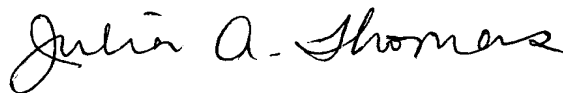
() that no item of information contained in the information disclosure statement was cited in a communication from a foreign patent office in a counterpart

foreign application or to the knowledge of the person signing the certification after making reasonable inquiry, was known to any individual designated in §1.56(c) more than three months prior to the filing of the statement. 37 CFR 1.97(e)(2).

The person making this certification is the attorney who signs below on the basis of the information:

- ☐ supplied by the inventor(s)
- ☐ supplied by an individual designated in §1.56(c)
- ☒ in the attorney's file

Respectfully submitted,

A handwritten signature in cursive script that reads "Julia A. Thomas".

Julia A. Thomas
Reg. No. 52,283

Customer No. 22862



Form 1449 (Modified) Information Disclosure Statement By Applicant (Use Several Sheets if Necessary)	Atty. Docket No. SCHO0059	Serial No.: 09/868,156
	Applicant: Neumeier et al.	
	Filing Date: September 14 2001	Group: 2831

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear		
		4,586,109	04/29/1986	Peters et al.			
		5,719,069	02/17/1998	Sparks			
		5,744,752	04/28/1998	Chen et al.			

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear		
		195 34 137	03/20/1997	Germany			

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Description of DE-A1-195 34 137

DE-A1-195 34 137 relates to a micro valve arrangement, in which recesses are formed in the surface of a semiconductor layer and separated from each other by a central rip. The surface of the layer is covered by a membrane. The membrane is connect to the semiconductor layer by anode bonding except over the rip and forms, along with the recesses, two chambers. The membrane can be lifted to form a gap between the rip and the membrane making use of the piezoelectric device, allowing liquid or gas to pass between the rip and the membrane. Fluid channels fluidically connecting the chambers to the outside are provided in the semiconductor layer. This document does not include any hint as to electronic components in a thinned semiconductor wafer.